

I-PAT[®]

Innovative, automated inline screening solution

BENEFITS:	I-PAT [®] (Inline Defect Part Average Testing) runs on KLA's 8 Series high productivity and Puma™ laser scanning inspection systems as a fully automated solution. I-PAT identifies die with outlier defect populations across critical process steps, helping automotive chipmakers:
	 Remove at-risk chips (chips with potential reliability failures) in the fab before they enter the supply chain
	 Improve decisions on which chips meet automotive quality standards through combination with end-of-line electrical test data
	 Reduce the rates of overkill (incorrectly calling a good chip bad) and underkill (incorrectly calling a bad chip good)
C O M P O N E N T S I N T E G R A T E D I N I - P A T S O L U T I O N :	 KLA's patterned wafer inspection systems produce the inline defect data needed for die- level screening. Through high speed, low cost inspection at required sensitivity, the 8 Series and Puma inspectors find defects across 100% of lots and 100% of die for critical process layers.
	 The Defect DNA[™] engine extracts comprehensive defect characteristics during runtime on the inspection systems. The digital fingerprint of each defect plays a key role in understanding whether or not a defect will cause future reliability issues.
	 I-PAT Analyzer powered by SPOT[™] leverages customized machine learning algorithms to analyze Defect DNA and return prediction results.
	 Klarity[®] Defect compiles prediction results from multiple process layers and performs statistical outlier analysis. A reliability index per die is calculated to determine which die should be considered high risk and removed from the supply chain.
A P P L I C A T I O N S :	 Inline die-level screening

Independent check of end-of-line electrical test results





MARKETS:

Chip manufacturing

automotive, IoT, 5G, consumer electronics, industrial (military, aerospace, medical), data centers

PLATFORM:

- Customizable
- Future extendibility to other KLA systems

SUPPORTED INSPECTORS:

- KLA's 8 Series high productivity patterned wafer inspectors
- KLA's Puma[™] 9850 and Puma[™] 9980 laser scanning patterned wafer inspectors